Trion PECVD process information

Equipment	Trion Orion PECVD
Synonyms	PECVD
Process Area	DEPOSITION

These pages list process information for the qualified material deposition recipes on the Trion PECVD system, including recipe parameters, physical and optical film characteristics, and etch behaviour using standard etch recipes.

- Trion PECVD nitride_historical (Si3N4) Recipe Information
- Trion PECVD Nitride_Standard (Si3N4) Recipe Information
- Trion PECVD Oxide_Standard (SiO2) Recipe Information
- Trion PECVD process information update 2021